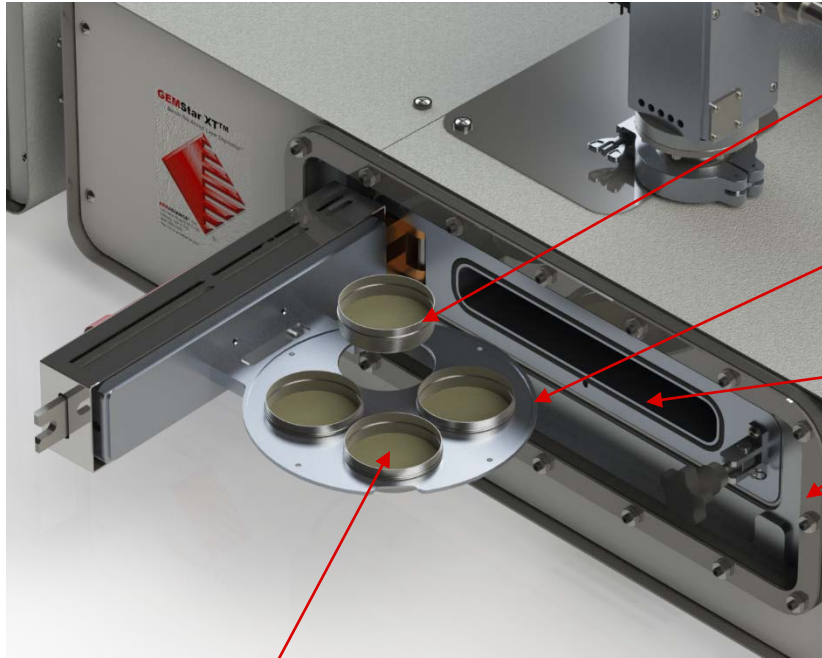


ARR-850860-8 GEMStar XT Particle Canister Mount With 50ml (ccm) Particle Canister Option



Supports up to four particle canisters
Each canister supports 12.5 ml (ccm)
Will process 50 ml (ccm) simultaneously

Will Process STD 200 mm wafer with same
chuck (Other options available)

Up to 300°C process temperature

Glove Box interface option available
If you need to protect your materials from
Atmosphere

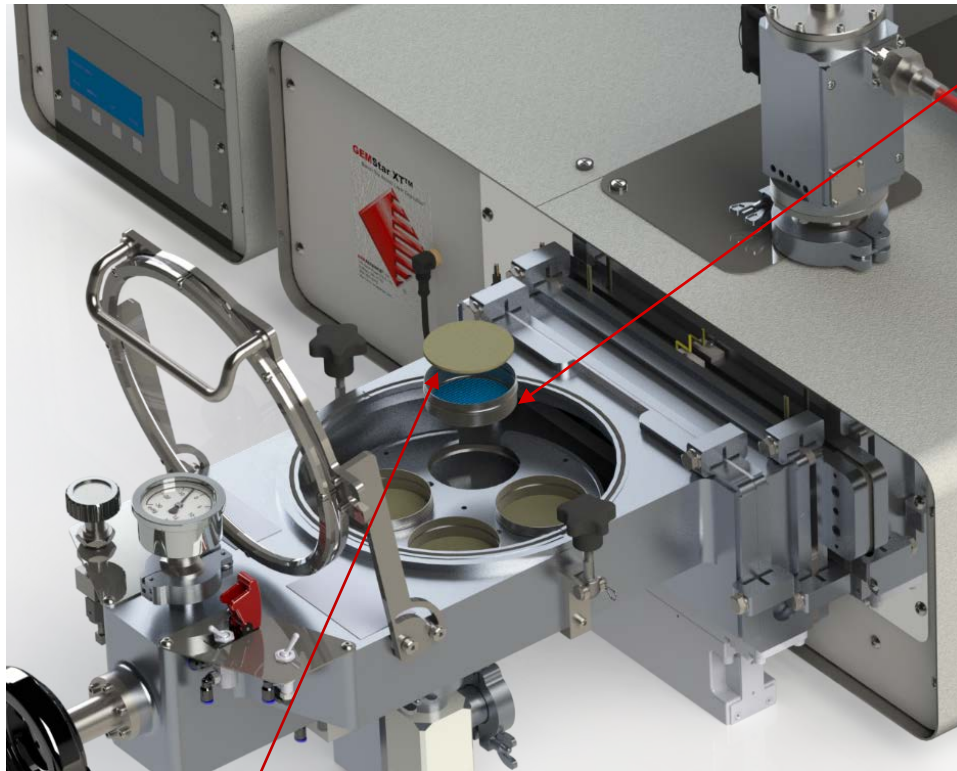


Process Technology

Thin particle layer up to 3.4 mm and expo process mode to achieve deep
coating penetration for Thermal and many PEALD applications

*The equipment you need to find the best solution for your Atomic Layer
Deposition material research no longer requires most of your budget*

GEMStar XT Load Lock With 50ml (ccm) Particle Canister Option



Supports up to four particle canisters
Each canister supports 12.5 ml (ccm)
Will process 50 ml (ccm) simultaneously

Will Process STD 200 mm wafer with
same chuck

Up to 300°C process temperature

Process Technology

Thin particle layer up to 3.4 mm and expo process mode to achieve deep coating penetration for Thermal and many PEALD applications